TRA	NSMITTAL FORM orrespondence after initial filing)	Application Number Filing Date First Named Inventor Art Unit Examiner Name Attorney Docket Number	Approved for use through 08/30/2003. OMB 0651-0031 at and Trademark Office; U.S. DEPARTMENT OF COMMERCE on of information unless it displays a valid OMB control number. 10/714,088 November 14, 2003 Sidlgata V. Sreenivasan Unassigned P69-11-03
Amendment/f After I Affida Extension of Express Abar Information D Certified Coppocument(s) Response to Incomplete A	tal Form Ittached Reply Final vits/declaration(s) Time Request Indonment Request visclosure Statement y of Priority Missing Parts/	Drawing(s) Licensing-related Papers Petition Petition to Convert to a Provisional Application Power of Attorney, Revocation Change of Correspondence Addre Terminal Disclaimer Request for Refund CD, Number of CD(s)	After Allowance communication to Technology Center (TC) Appeal Communication to Board of Appeals and Interferences Appeal Communication to TC (Appeal Notice, Brief, Reply Brief) Proprietary Information
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: McMackin et al. PATENT APPLICATION

Serial No.: 10/714,088 Group Art Unit: Unassigned Filing Date: October 2, 2003 Examiner: Unassigned

For: DISPENSE GEOMETRY TO ACHIEVE HIGH SPEED FILLING AND

THROUGHPUT

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents

Alexandria, VA 22313-1450

Sir:

The following information is submitted in compliance with Applicants' duty of disclosure under 37 C.F.R. § 1.56. Form PTO-1449 and a copy of each reference recited below accompanies this document. It is respectfully requested that the cited information be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

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CERTIFICATE OF MAILING

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Respectfully,

Kenneth C. Brooks Reg. No. 38,393

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 1 of 6

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Application Number	10/714,088			
Filing Date	11/14/2003			
First Named Inventor	McMackin et al.			
Group Art Unit	Unassigned			
Examiner Name	Unassigned			
Attorney Docket Number	P69/MII-29-11-03			

		U.S. Patent Do	cument	i	Date of Publication of	Pages, Columns, Lines,
Examiner Initials*	Cite No. ¹	Number	Kind Code ² (if known)	Name of Patentee or Applicant of Cited Document	Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear
	B1	3,827,027		Heisler	04-30-1974	
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	B31	5,723;176		Keyworth et al.	03-03-1998	
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	B34	5,802,914		Fassler et al.	09-08-1998	
Examiner				<u> </u>	Date	
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Substitute	for form 1449A/PT	0		Comple	te if Known
				Application Number	10/714,088
INFO	RMATION I	DISC	LOSURE	Filing Date	11/14/2003
STAT	EMENT BY	/ AP	PLICANT	First Named Inventor	McMackin et al.
				Group Art Unit	Unassigned
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Sheet	2	of	6	Attorney Docket Number	P69/MII-29-11-03

				U.S. PATENT DOCUMEN	TS	4.9
Examiner Initials*	Cite No.1	U.S. Patent Do	Kind Code ² (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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	B50	6,204,922		Chalmers	03-20-2001	
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	B52	6,245,213		Olsson et al.	06-12-2001	
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STAT	TEMENT BY	AP	PLICANT	First Named Inventor	McMackin et al.
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				FOREIGN	PATENT DOCUMENTS			
Examiner Initials*	Cite No.1	Office ³	Foreign Patent Docume Number ⁴	nt Kind Code ⁵ (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
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	B54	wo	92/17883		Olsson	10-15-1982		
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Complete if Known Substitute for form 1449B/PTO 10/714,088 **Application Number** INFORMATION DISCLOSURE **Filing Date** 11/14/2003 STATEMENT BY APPLICANT McMackin et al. **First Named Inventor** Group Art Unit Unassigned (use as many sheets as necessary) **Examiner Name** Unassigned 6 of P69/MII-29-11-03 Sheet Attorney Docket Number

OTHER PRIC	R ART - I	NON PATENT LITERATURE DOCUMENTS	
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	B64	STEWART, "A Platform with Six Degrees of Freedom," Proc. of Inst. Mech. Engrs., 1965, pp. 371-378, vol. 180 pt. 1, no. 15.	
	B65	PAROS et al., "How to Design Flexure Hinges," Machine Design, Nov. 25, 1965, pp. 151-156.	
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	B71	SLOCUM, "Precision Machine Design: Macromachine Design Philosophy and its Applicability to the Design of Micromachines," Micro Electro Mechanical Systems, 1992, pp. 37-42.	
	B72	ARAI et al., "Calibration and Basic Motion of a Micro Hand Module," Proc. of IEEE, 1993, pp. 1660-1665.	
	B73	PENG et al., "Compliant Motion Control of Kinematically Redundant Manipulators," IEEE Transactions on Robotics and Automation, December 1993, pp. 831-837, vol. 9, no. 6.	
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				Application Number	10/714,088	
INF	DRMATION	DISC	LOSURE	Filing Date	11/14/2003	
STA	TEMENT B	Y API	PLICANT	First Named Inventor McMackin et al.		
				Group Art Unit	Unassigned	
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Sheet	5	of	6	Attorney Docket Number	P69/MII-29-11-03	

OTHER PRI	OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS						
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				Application Number	10/714,088	
INFORMATION DISCLOSURE				Filing Date	11/14/2003	
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